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| INFORMATION DISCLOSURE<br>STATEMENT BY APPLICANT | Complete if Known    |                    |
|--------------------------------------------------|----------------------|--------------------|
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|                                                  | First Named Inventor | Ulrich Speh, et al |
|                                                  | Group Art Unit       |                    |
|                                                  | Examiner Name        |                    |
|                                                  | Attorney Docket No.  | Az.3049            |

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